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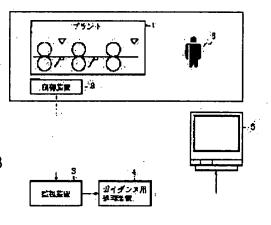
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(54) METHOD AND DEVICE FOR ABNORMALITY DIAGNOSIS

(57)Abstract:

PROBLEM TO BE SOLVED: To diagnose an abnormal plate thickness under rolling by calculating a deviation between the plate thickness of a rolling material t be rolled and a target plate thickness and recognizing the abnormal plate thickness when the deviation exceeds a reference value.

SOLUTION: A control device (measuring means) 2 measures the plate thickness of a rolling material. A monitor device (calculating means, recognizing means) 3 calculates a deviation between an actual plate thickness and a target plate thickness and the deviation is compared to a discrimination reference value of a plate thickness abnormality. In the cast that the deviation exceeds the discrimination reference value, it is



recognized as the plate thickness abnormal. It is desirable to detect a local min value and local max value of the plate thickness. A cause of the abnormality is desirably assumed by applying a cause assumption rule. As the cause assumption rule, an abnormal stand is assumed from an actual louver angle, an actual speed correction value for a stand mill, an actual torque and an actual rolling load of a mill motor etc. For example, a speed set value of a mill stand is corrected from the actual louver angle or a forwarding rate of the standard louver is

corrected from the speed correction value.

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